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(12) **United States Design Patent** (10) **Patent No.: US D851,140 S**
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(54) **PRESSING MEMBER FOR SUBSTRATE POLISHING APPARATUS**

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(73) Assignee: **EBARA CORPORATION**, Tokyo (JP)

(**) Term: **15 Years**

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Aug. 5, 2016	(JP)	2016-016854
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(52) **U.S. Cl.**
USPC **D15/126**
(58) **Field of Classification Search**
USPC D8/70, 71; D15/126, 138
CPC B24B 9/065; B24B 21/004; B24B 37/27
See application file for complete search history.

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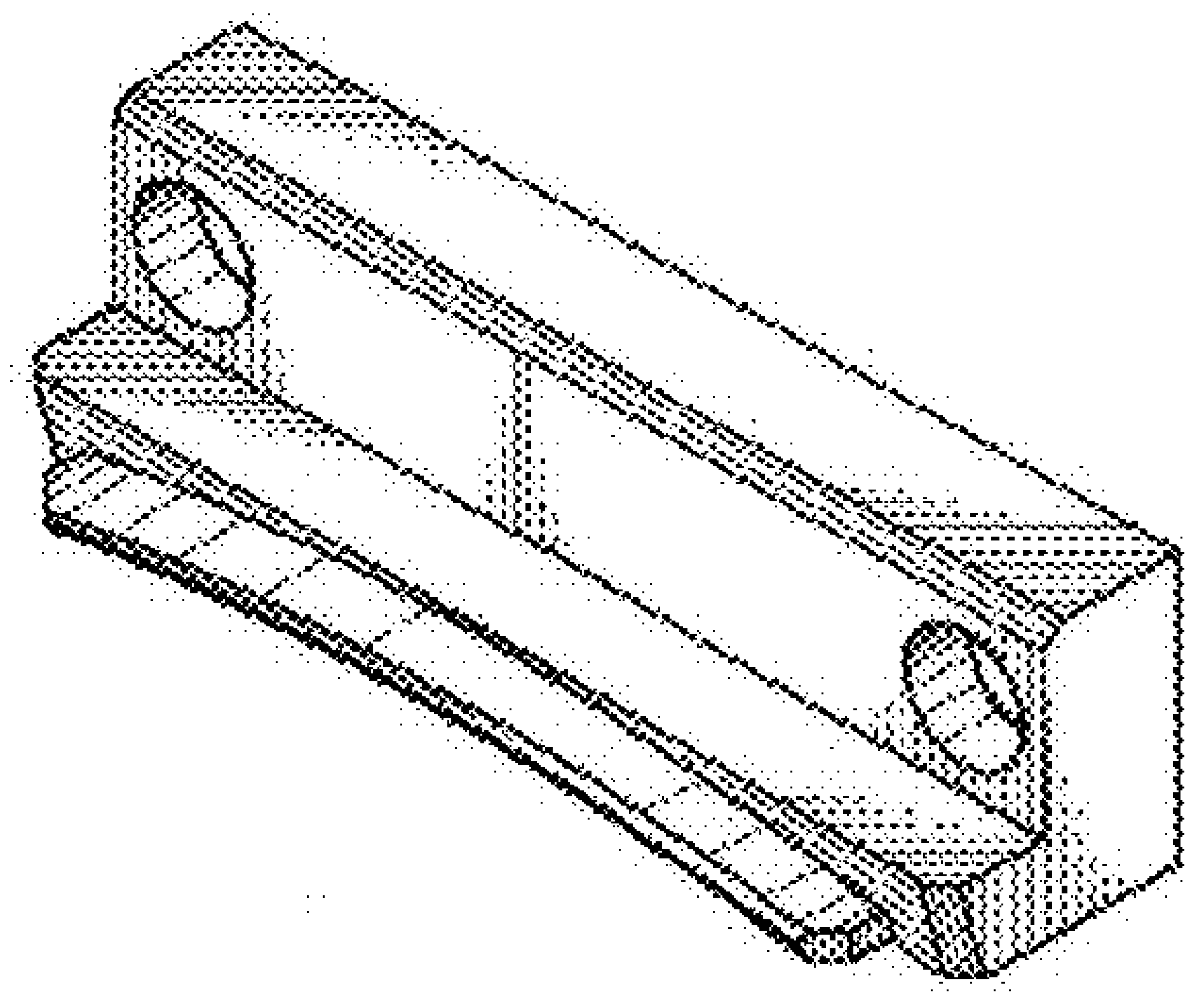
(57) **CLAIM**

The ornamental design for a pressing member for a substrate polishing apparatus, as shown and described.

DESCRIPTION

FIG. **1** is a first perspective view, observed from a front of a pressing member for a substrate polishing apparatus showing our new design;
FIG. **2** is a second perspective view, observed from a rear thereof;
FIG. **3** is a front view thereof;
FIG. **4** is a rear view thereof;
FIG. **5** is a top view thereof;
FIG. **6** is a bottom view thereof; and,
FIG. **7** is a right-side view thereof, a left-side view being a mirror image thereof.

1 Claim, 2 Drawing Sheets



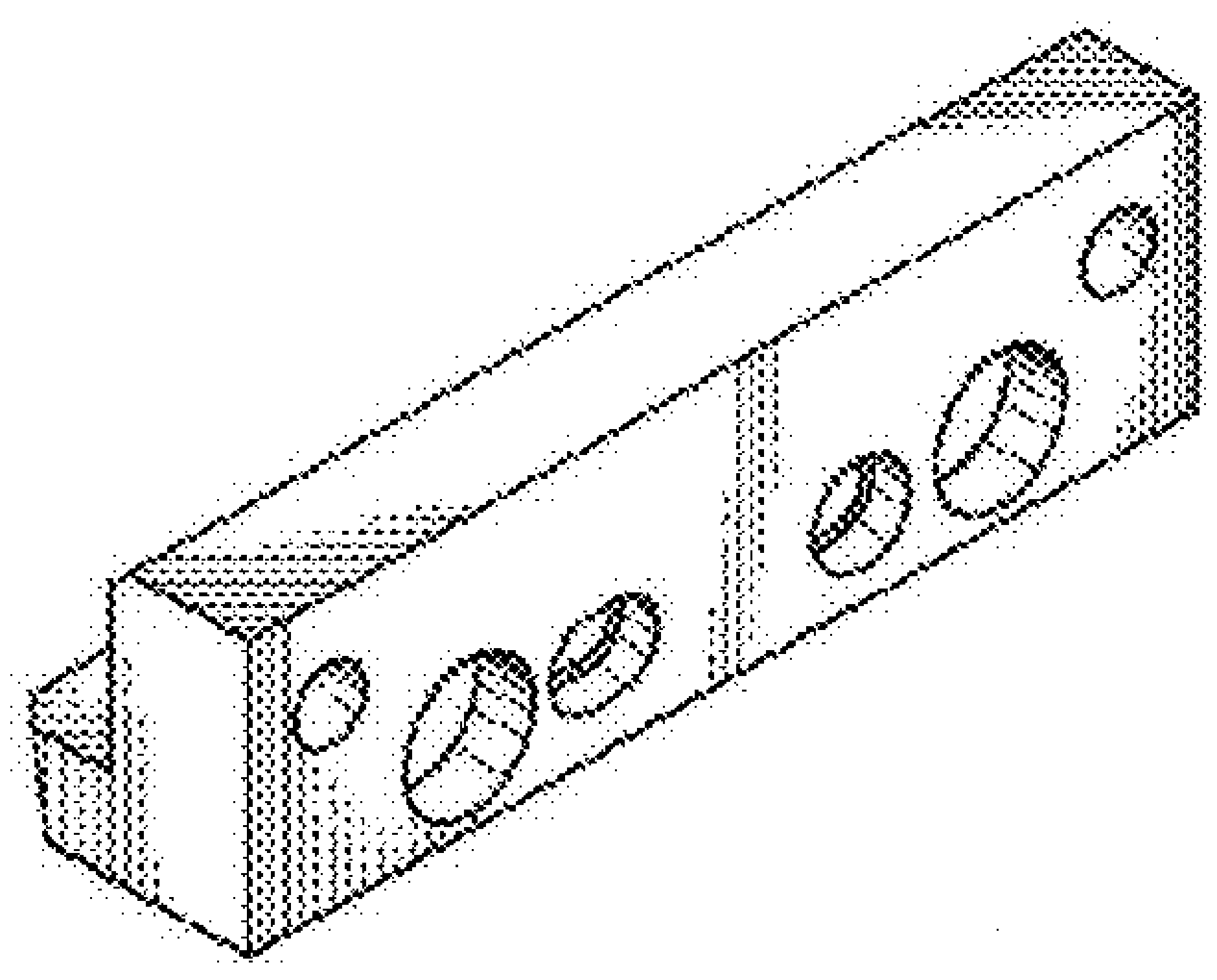


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FIG.1

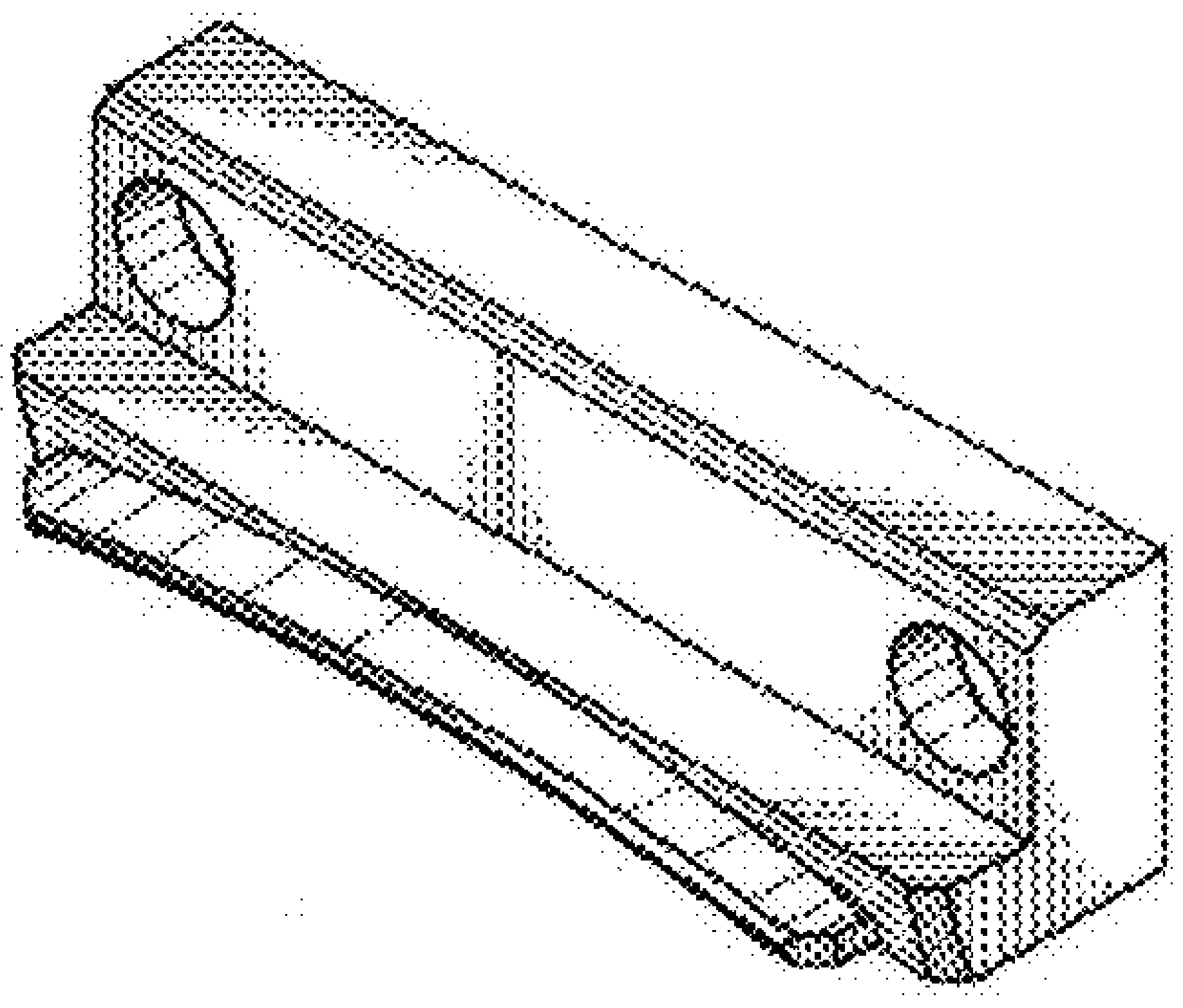

FIG.2

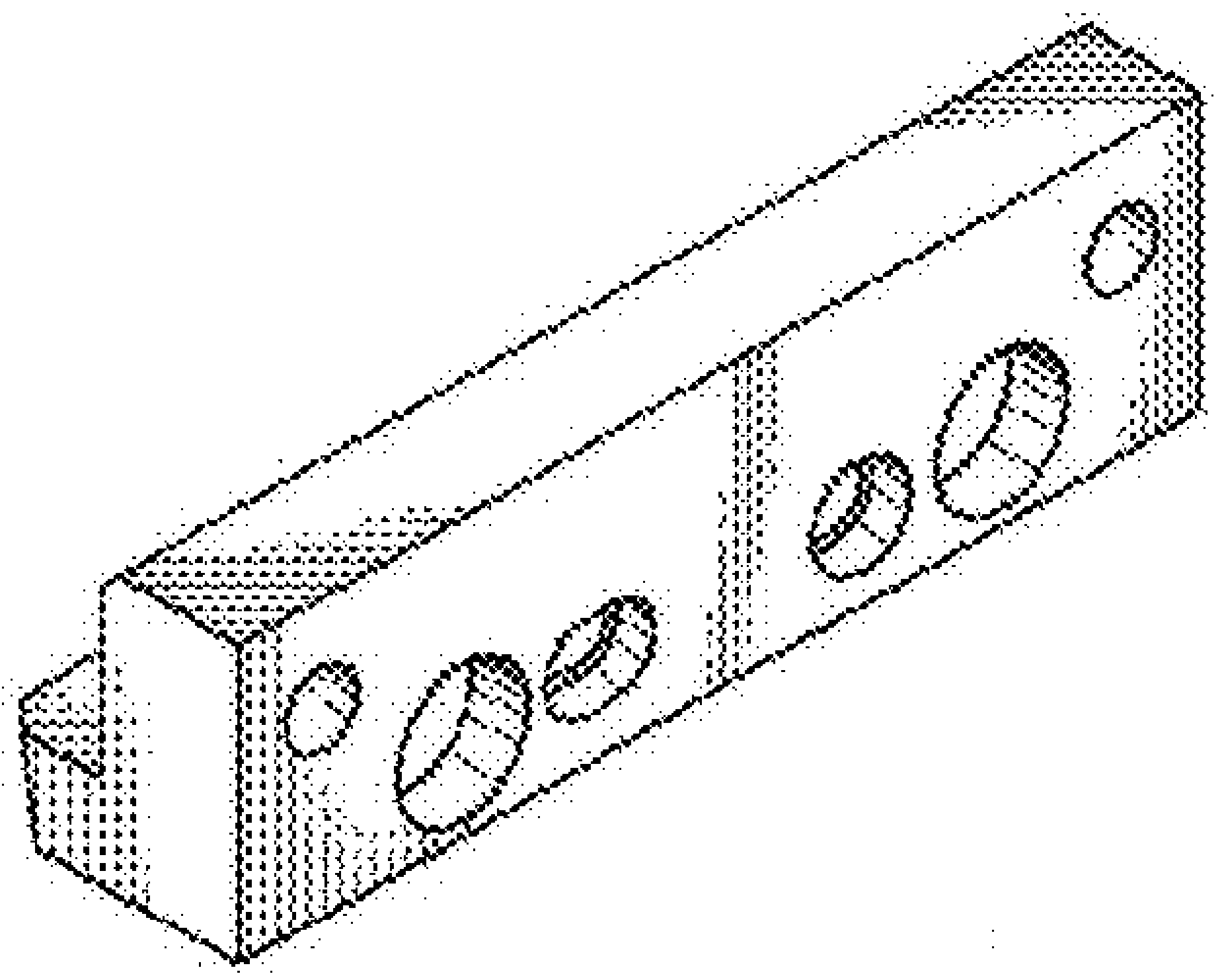

FIG.3

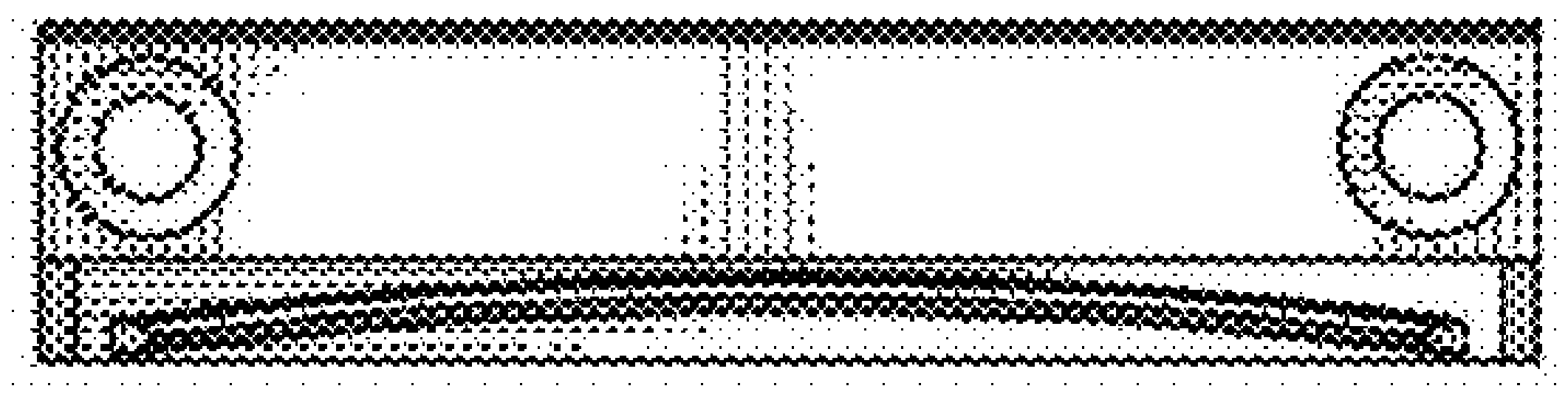

FIG.7

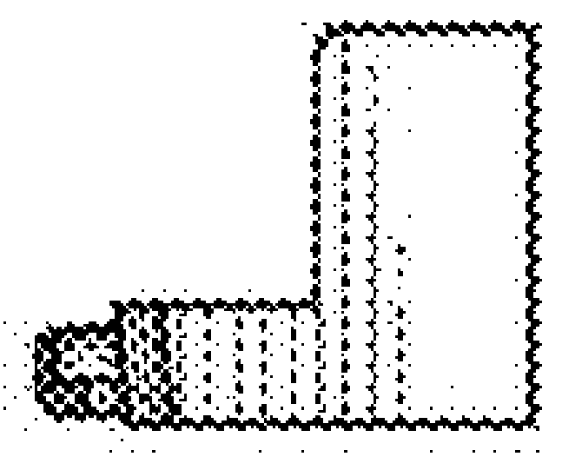

FIG.4

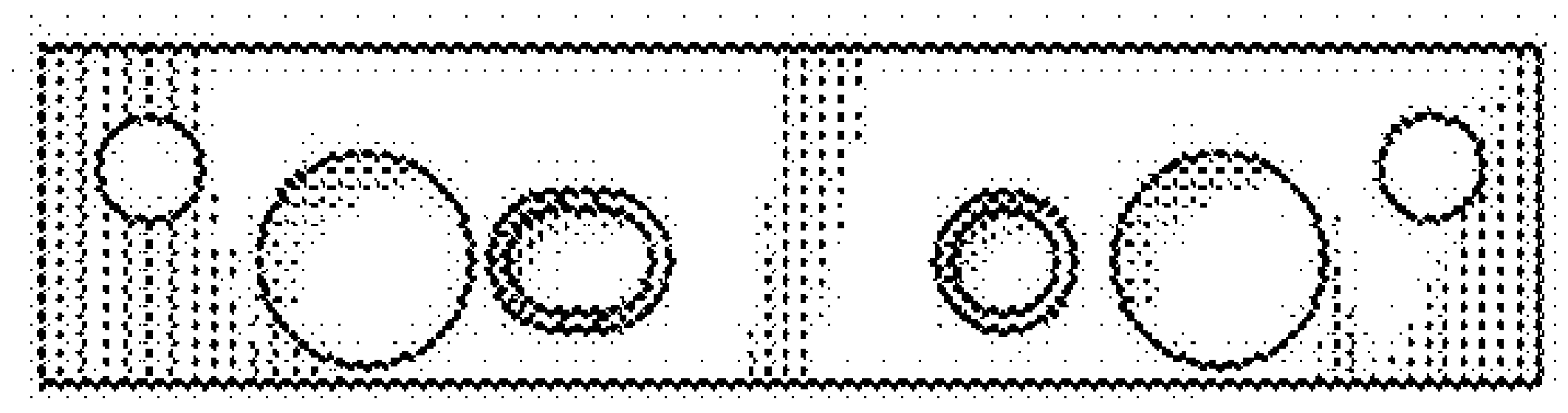

FIG.5

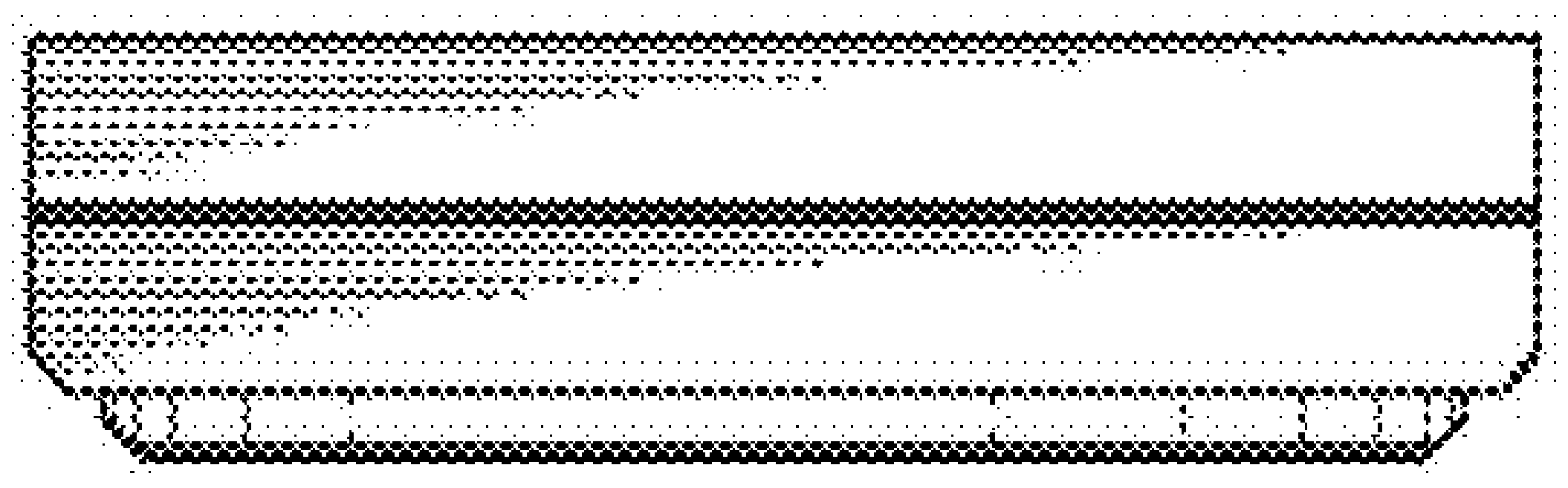

FIG.6